



*Handwritten initials/signature in the top right corner.*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Katsutoshi Izumi et al

Group Art Unit: 2813

Serial No.: 10/802,806

Examiner: Heather Anne Doty

Filed: March 18, 2004

P.T.O. Confirmation No.: 5100

For: MANUFACTURING METHOD FOR BURIED INSULATING LAYER-TYPE  
SEMICONDUCTOR SILICON CARBIDE SUBSTRATE

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Date: June 14, 2006

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated February 21, 2006, for one month from May 21, 2006 to June 21, 2006.

Attached please find a check in the amount of \$120.00, to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, KRATZ, QUINTOS, HANSON & BROOKS, LLP

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Attorney for Applicants  
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Atty. Docket No. 021740A  
Suite 1000, 1725 K Street, N.W.  
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(202) 659-2930  
DWH/nk



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PATENT TRADEMARK OFFICE

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